

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

The application of: Koos et al.

Attorney Docket No.: NOVLP068/NVLS-2818

Application No.: 10/690,084

Examiner: Vinh, Lan

Filed: October 20, 2003

Group: 1765

Title: METHOD FOR FABRICATION OF SEMICONDUCTOR INTERCONNECT

STRUCTURE WITH REDUCED

CAPACITANCE, LEAKAGE CURRENT, AND

IMPROVED BREAKDOWN VOLTAGE

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the U.S. Postal Service with sufficient postage as first-class mail on December 1, 2005 in an envelope addressed to the Comprissioner for Patents, P.O. Box 1450

Alexandria, VA 2231/3/1450

Signed:

eslie Russell

RESPONSE A

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

This is in response to the non-final Office Action mailed August 5, 2005.

Amendments to the Claims are reflected in the listing of claims which begin on page 2 of this papers.

Remarks/Arguments begin on page 10 of this paper.